

FIG. 1

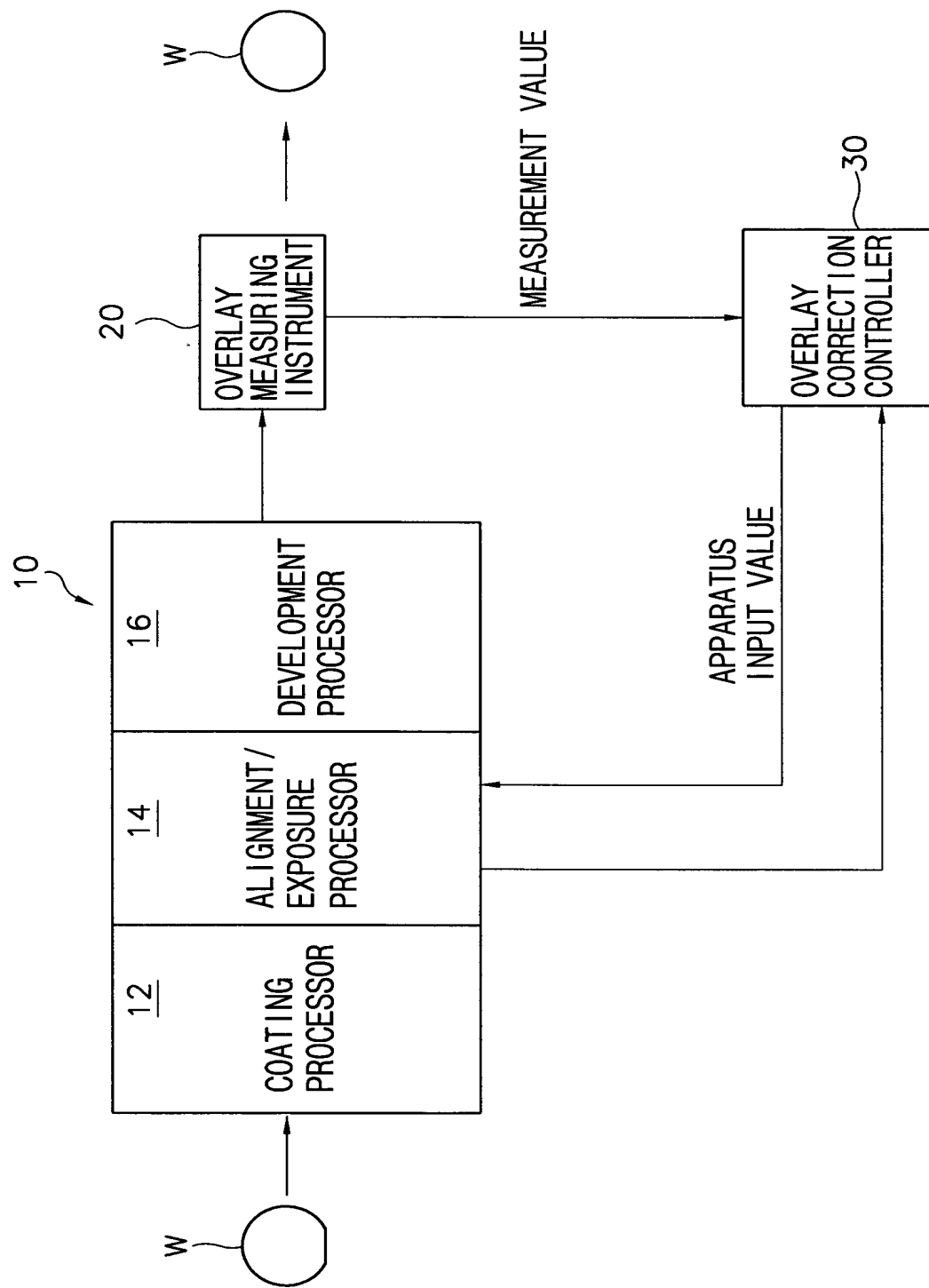


FIG. 2

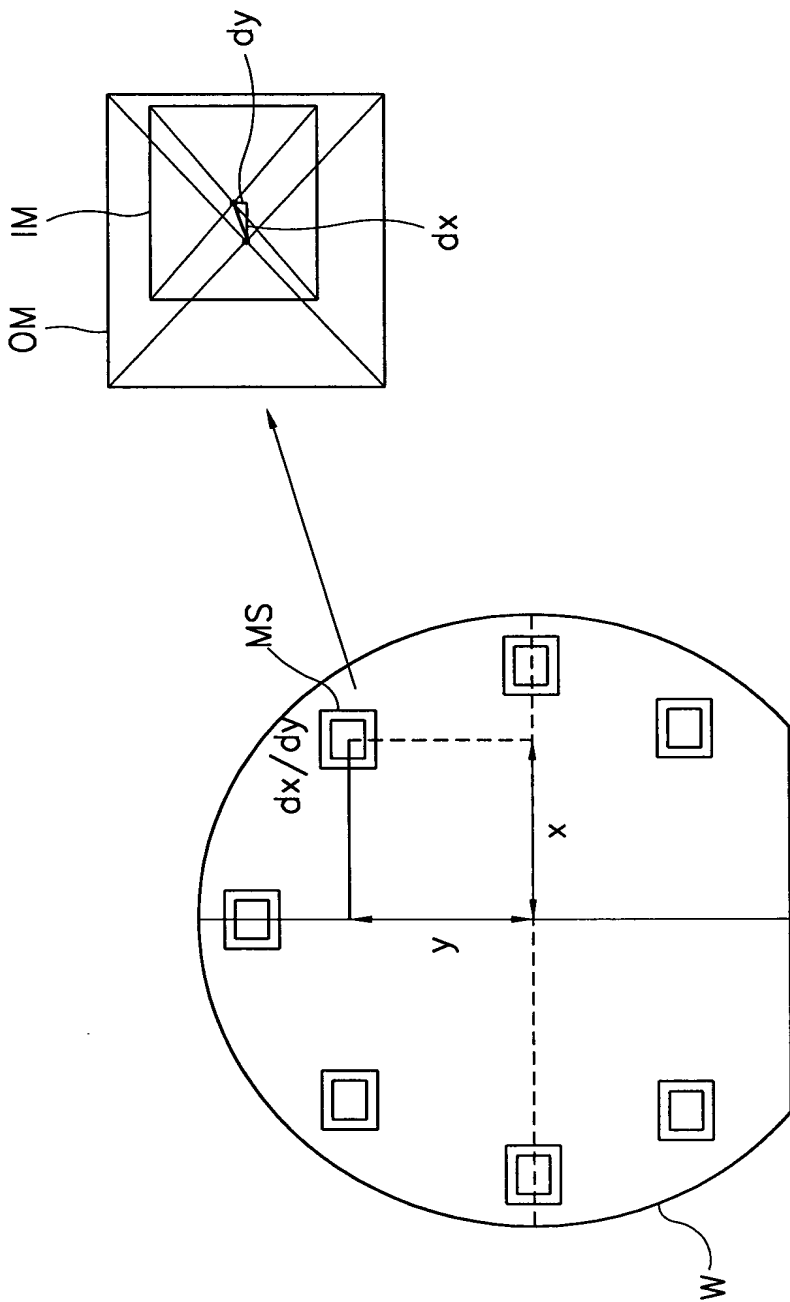


FIG. 3

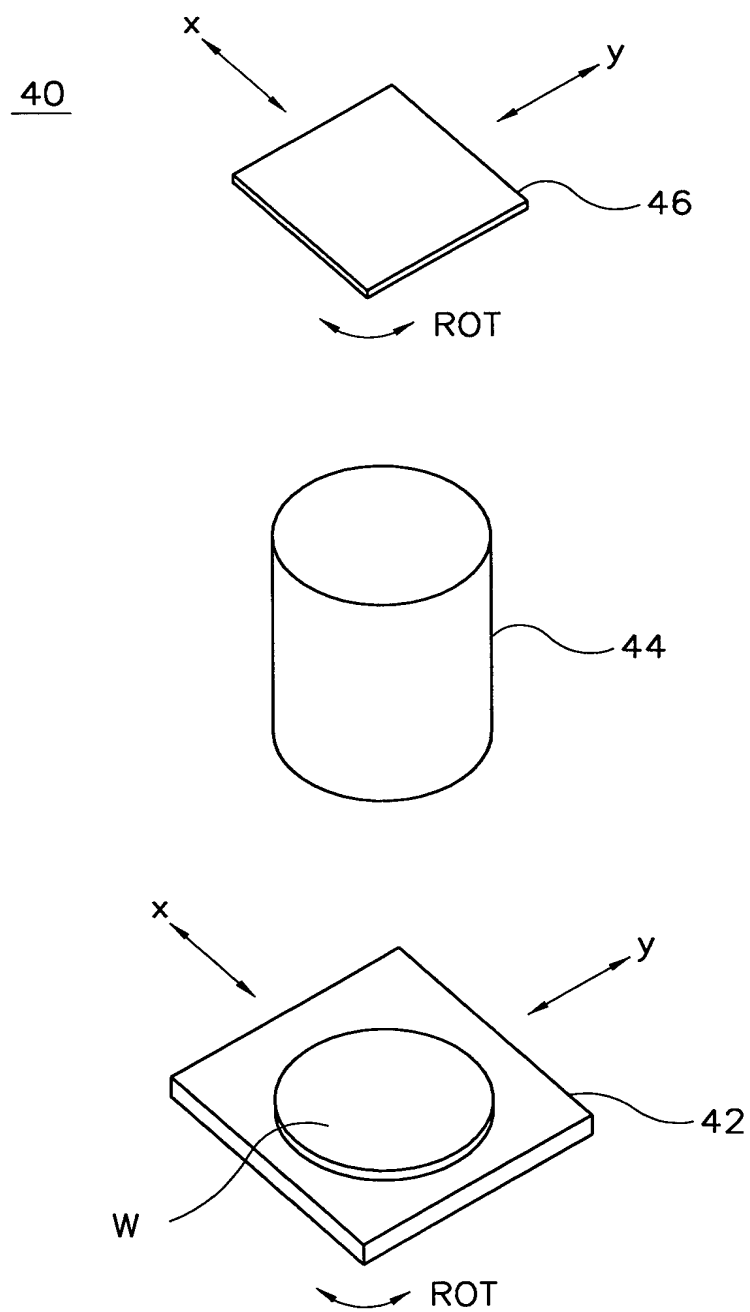


FIG. 4

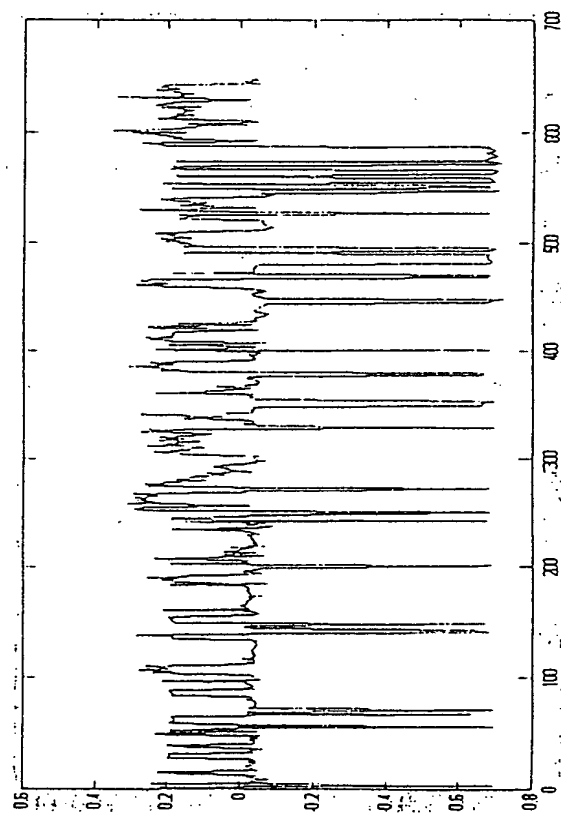
MEASURING TIME
LOT ID
OF-X
OF-Y
SC-X
SC-Y
ORT
W-ROT
RED-X
RED-Y
ROT-X
ROT-Y

20250720 10:00:00

FIG. 5

GENERATING TIME			
LOT ID			
FWD OF-X	RET OF-X	NN OF-X	IN OF-X
OF-Y	OF-Y	OF-Y	OF-Y
SC-X	SC-X	SC-X	SC-X
SC-Y	SC-Y	SC-Y	SC-Y
ORT	ORT	ORT	ORT
W-ROT	W-ROT	W-ROT	W-ROT
RED-X	RED	RED	RED
RED-Y			
ROT-X	ROT	ROT	ROT
ROT-Y			

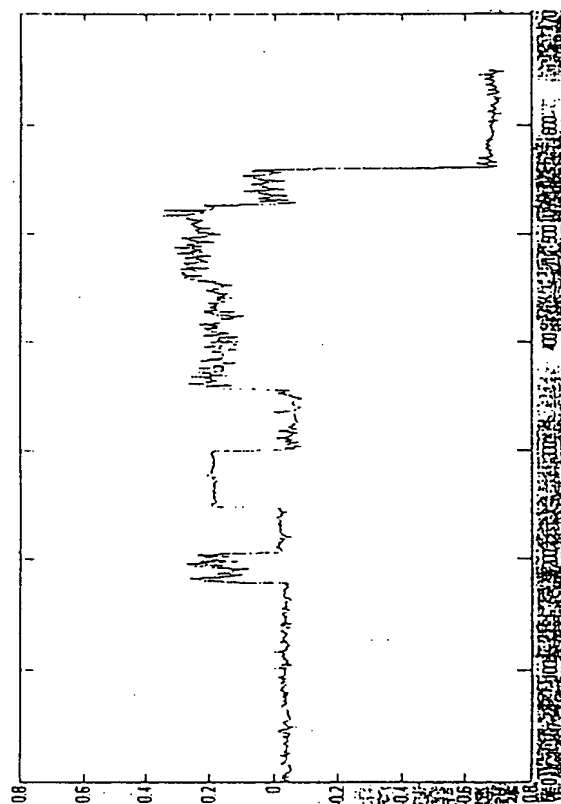
FIG. 6



CORRECTION APPARATUS INPUT (TIME SEQUENCE)

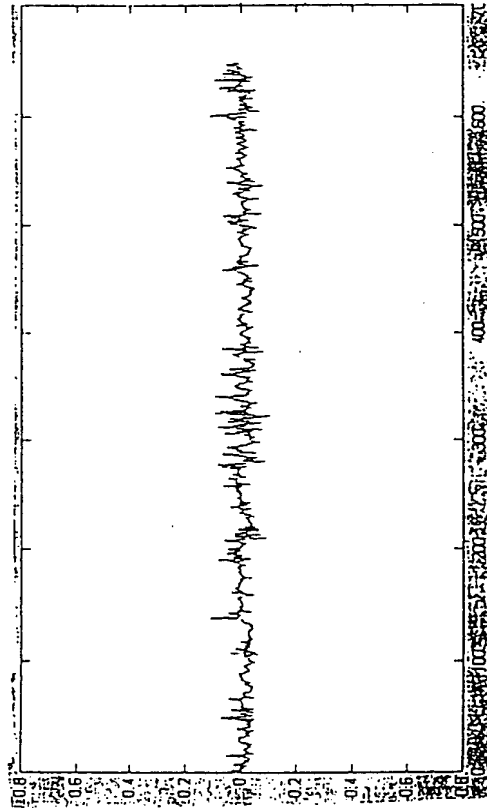
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FIG. 7



[illegible]

86



CORRECTION APPARATUS INPUT AFTER SUBTRACTING  
MEAN VALUE PER IDENTICAL HISTORY



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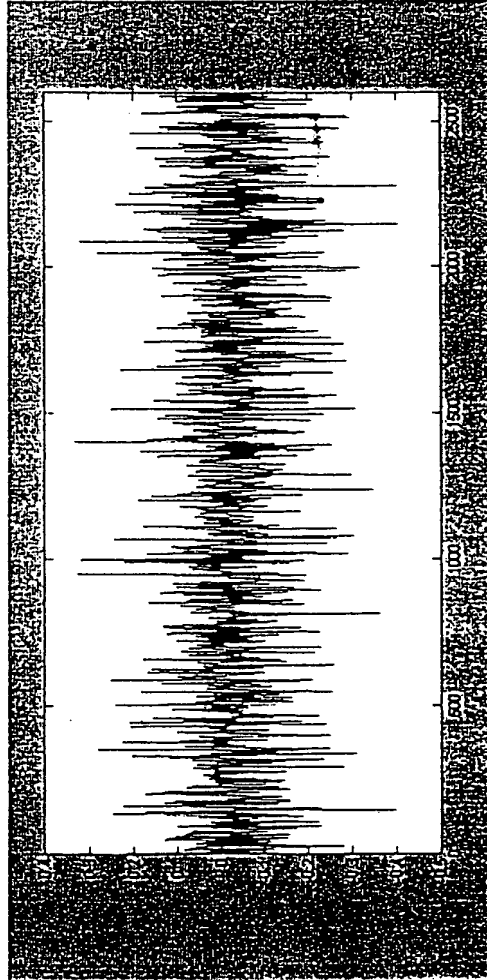
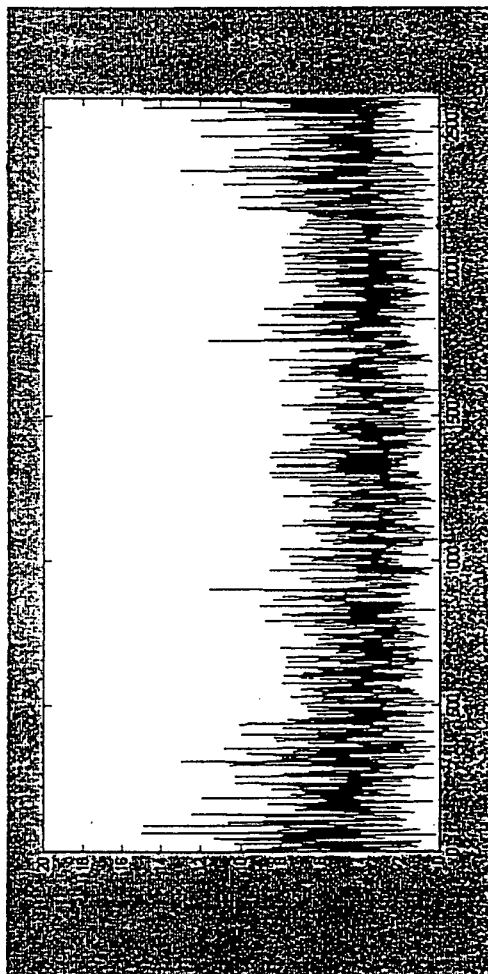
 $x(n)$  OF SAMPLE APPARATUS 1 WITH RESPECT TO OFFSET- $x$

FIG. 10



FREQUENCY SPECTRUM OF  $x(n)$

FIG. 11

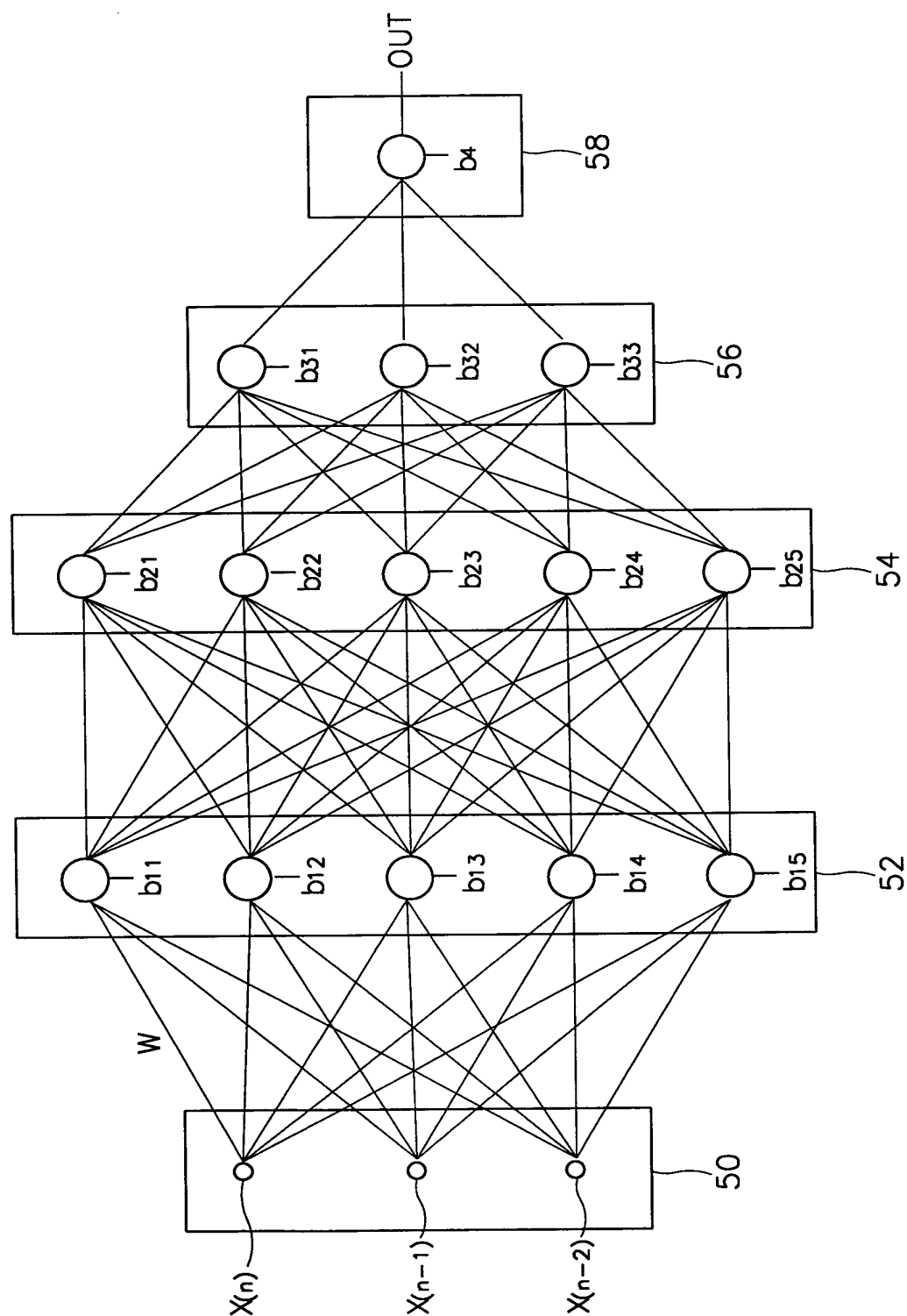


FIG. 12

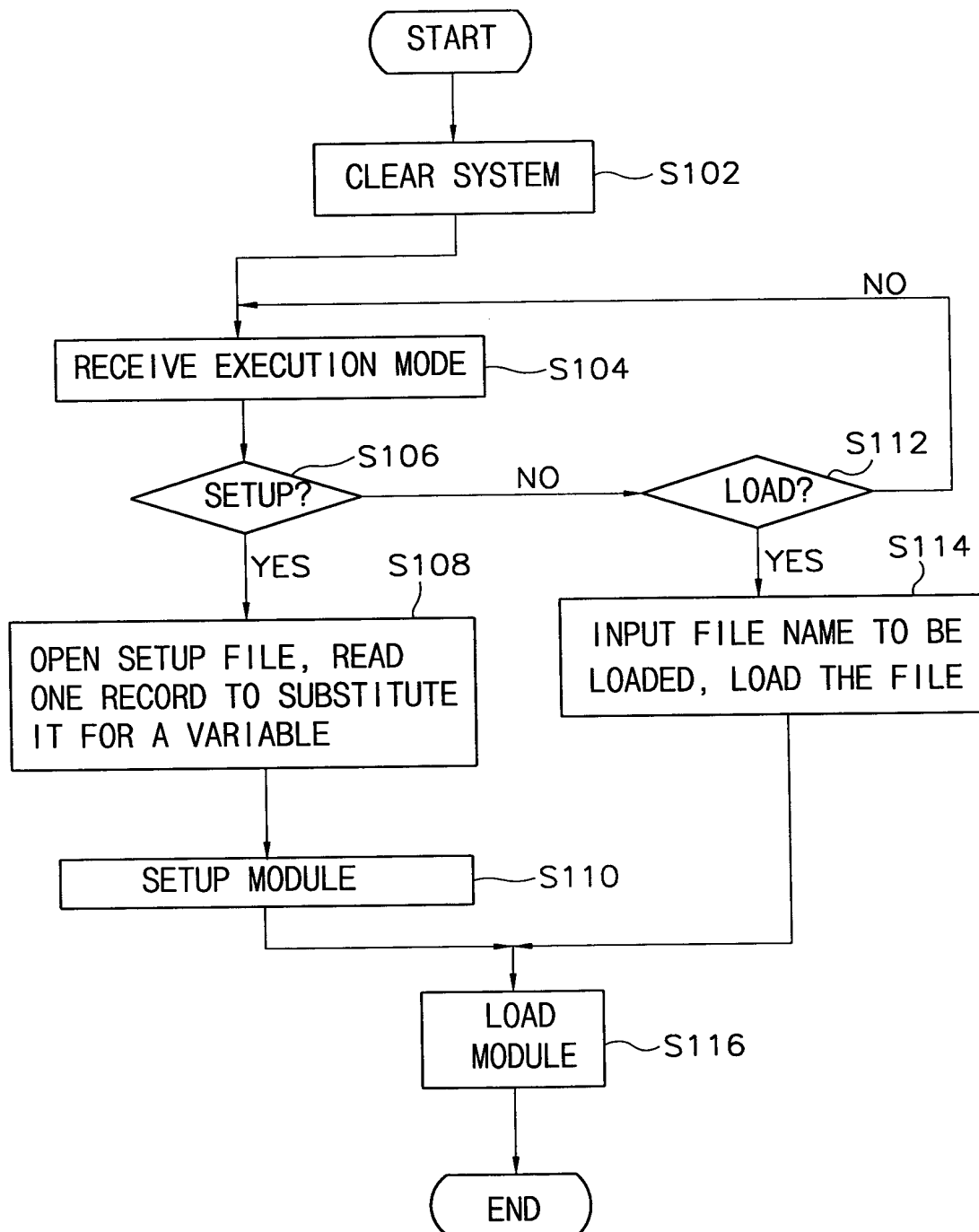


FIG. 13A

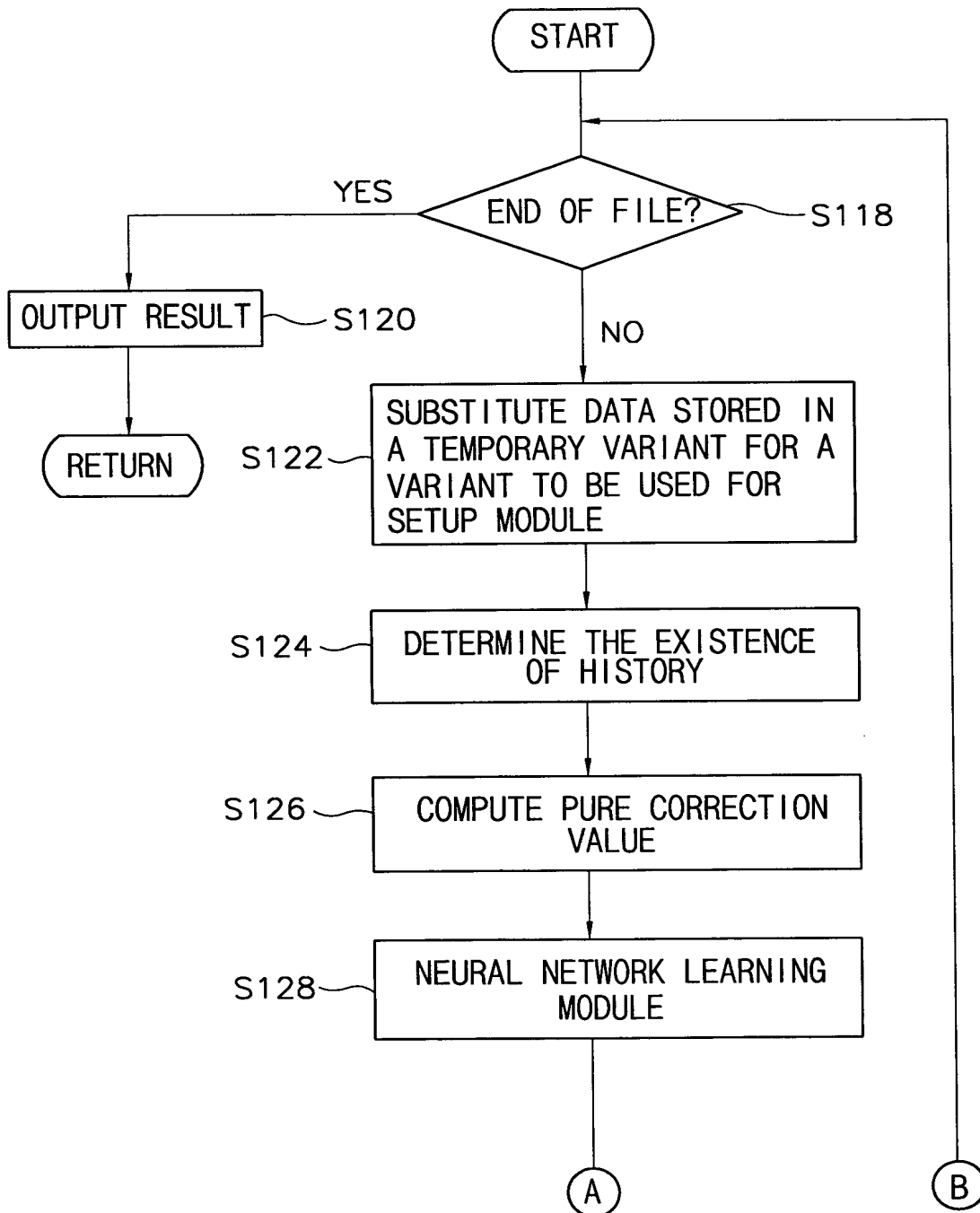


FIG. 13B

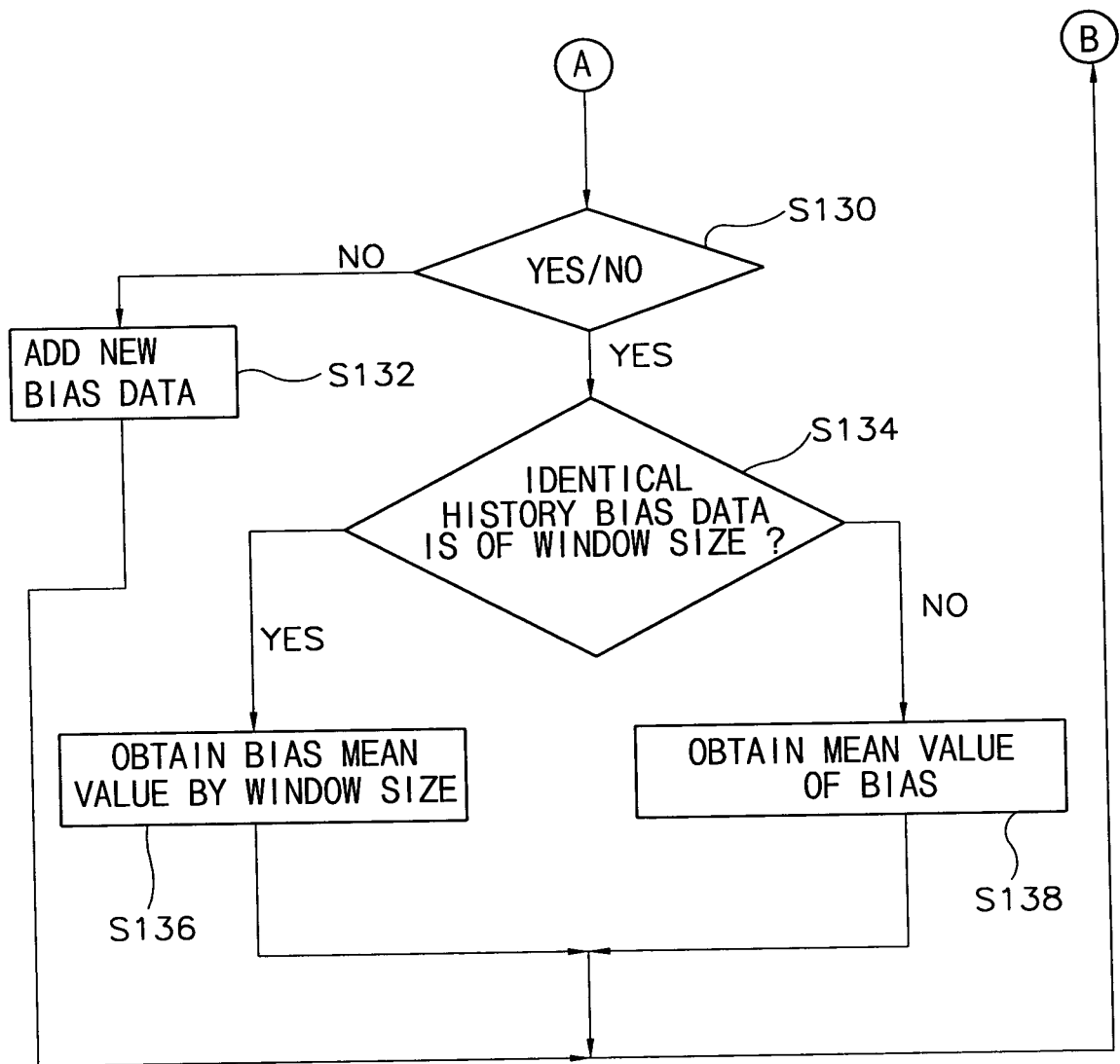


FIG. 14

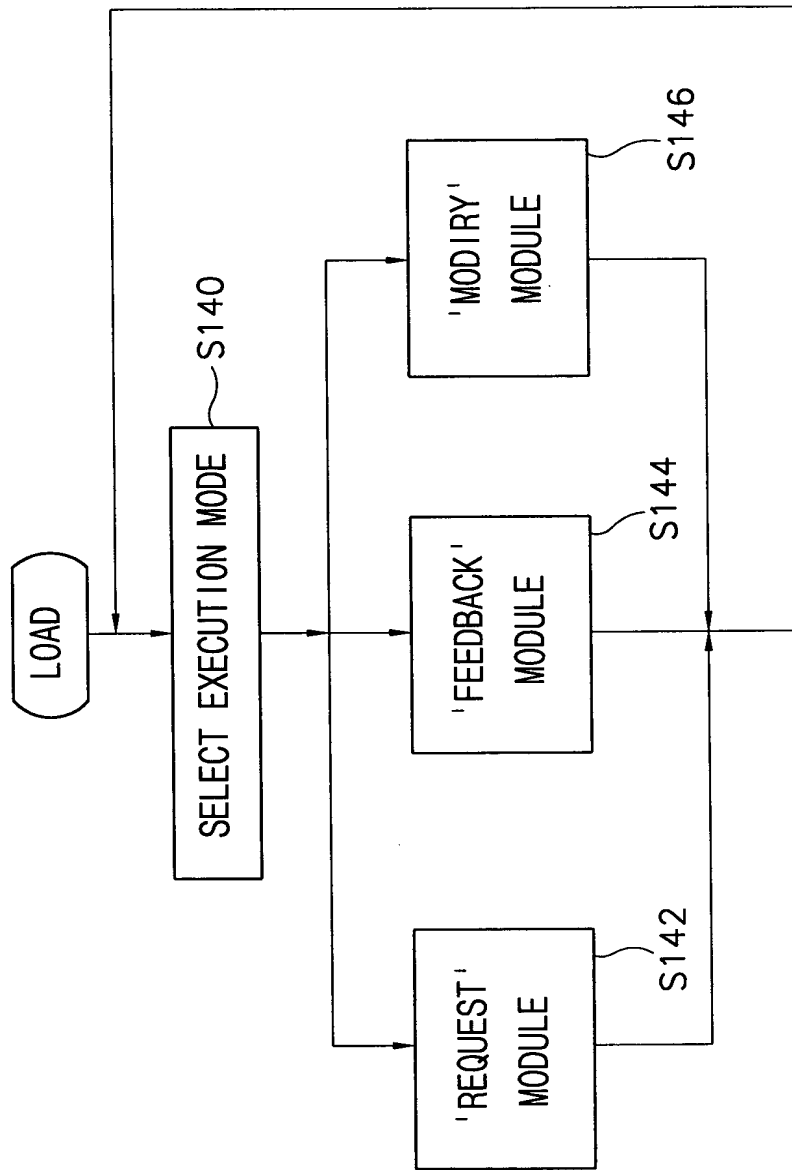


FIG. 15

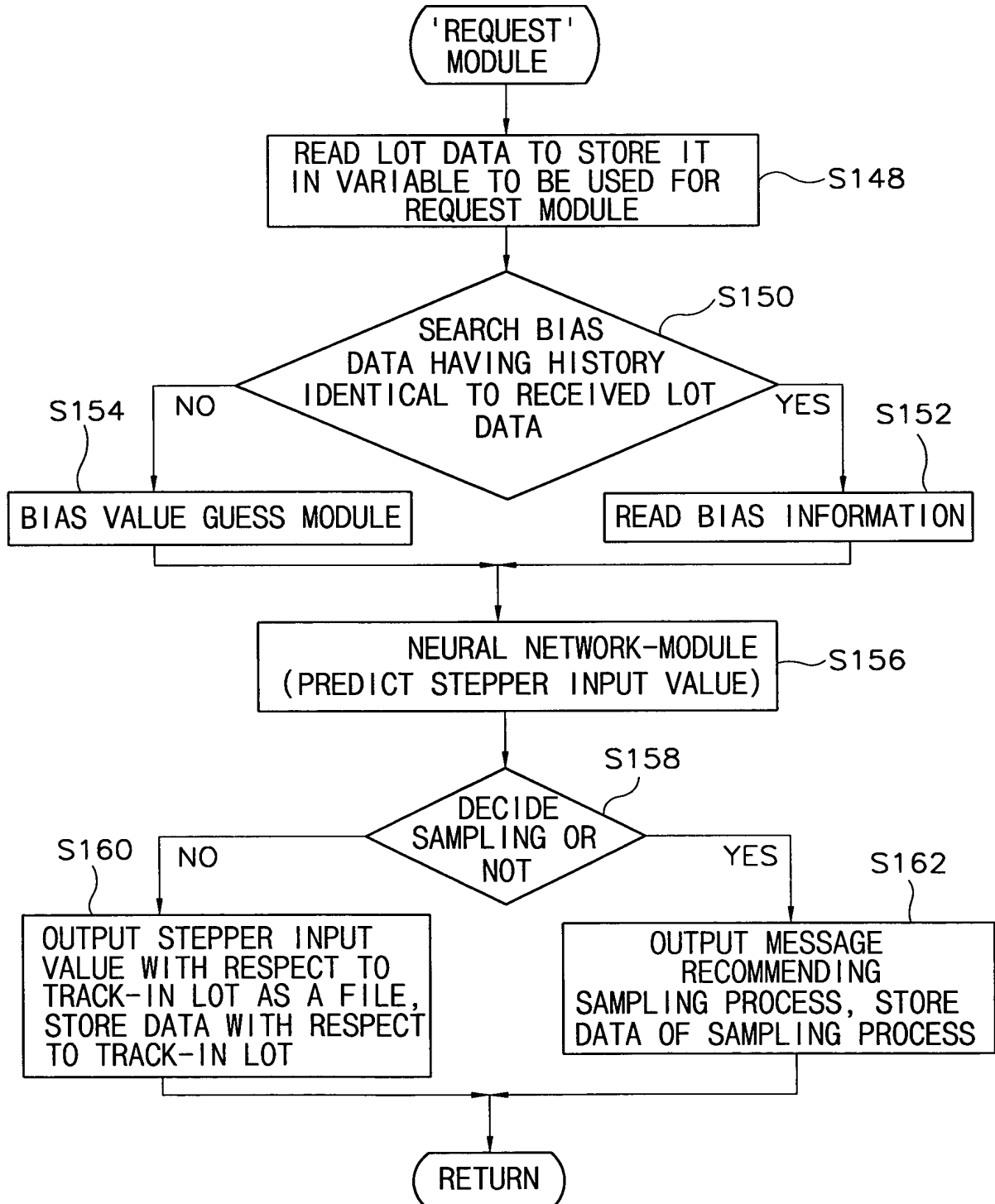




FIG. 16

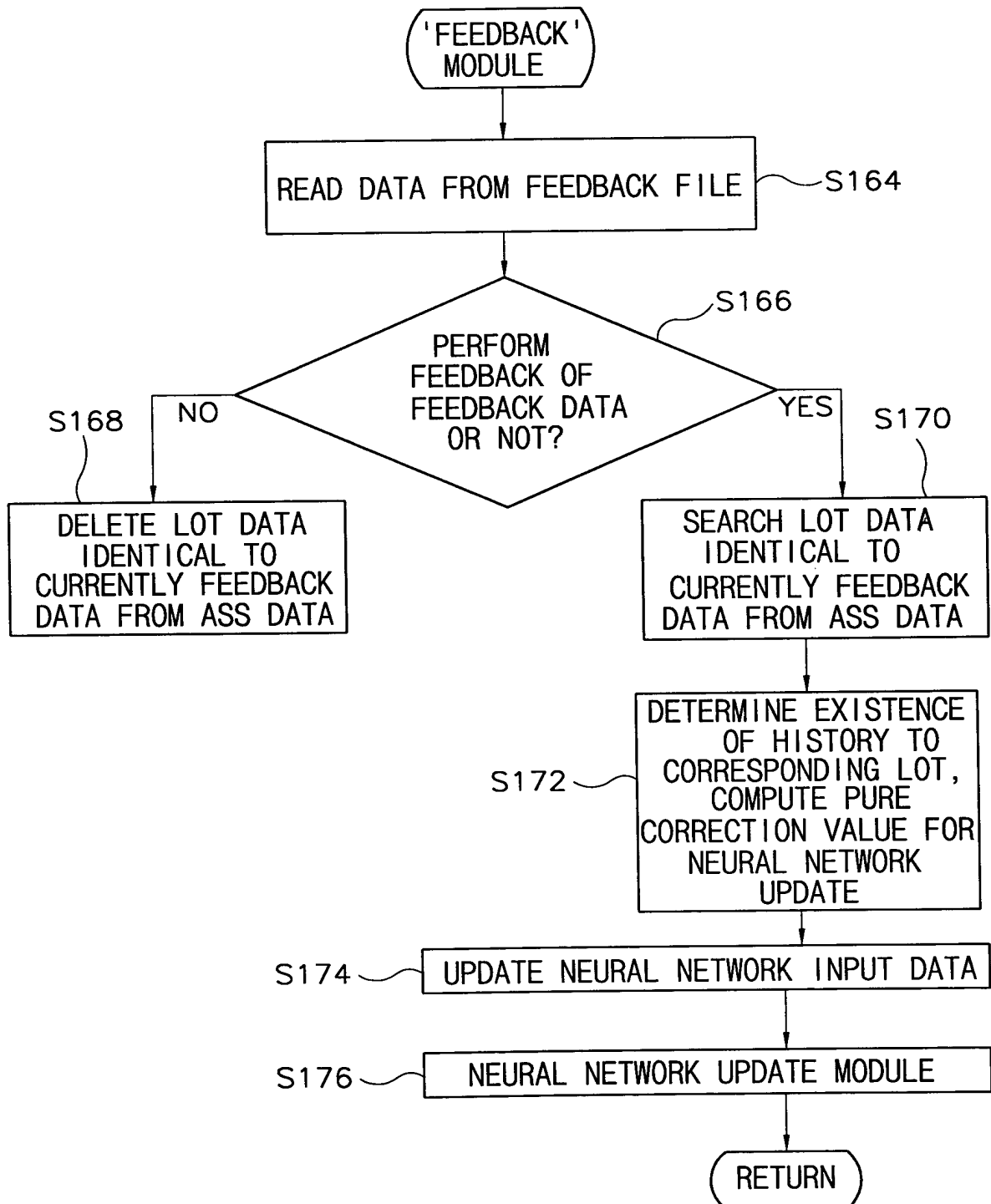


FIG. 17

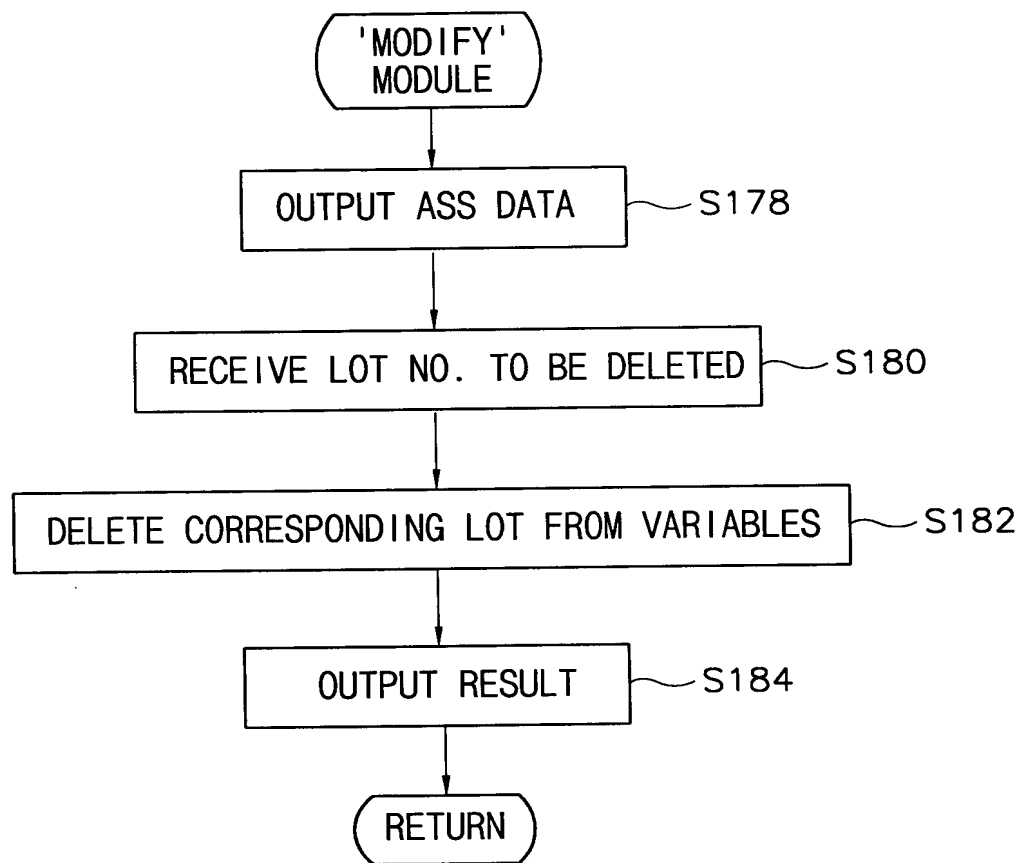


FIG. 18A

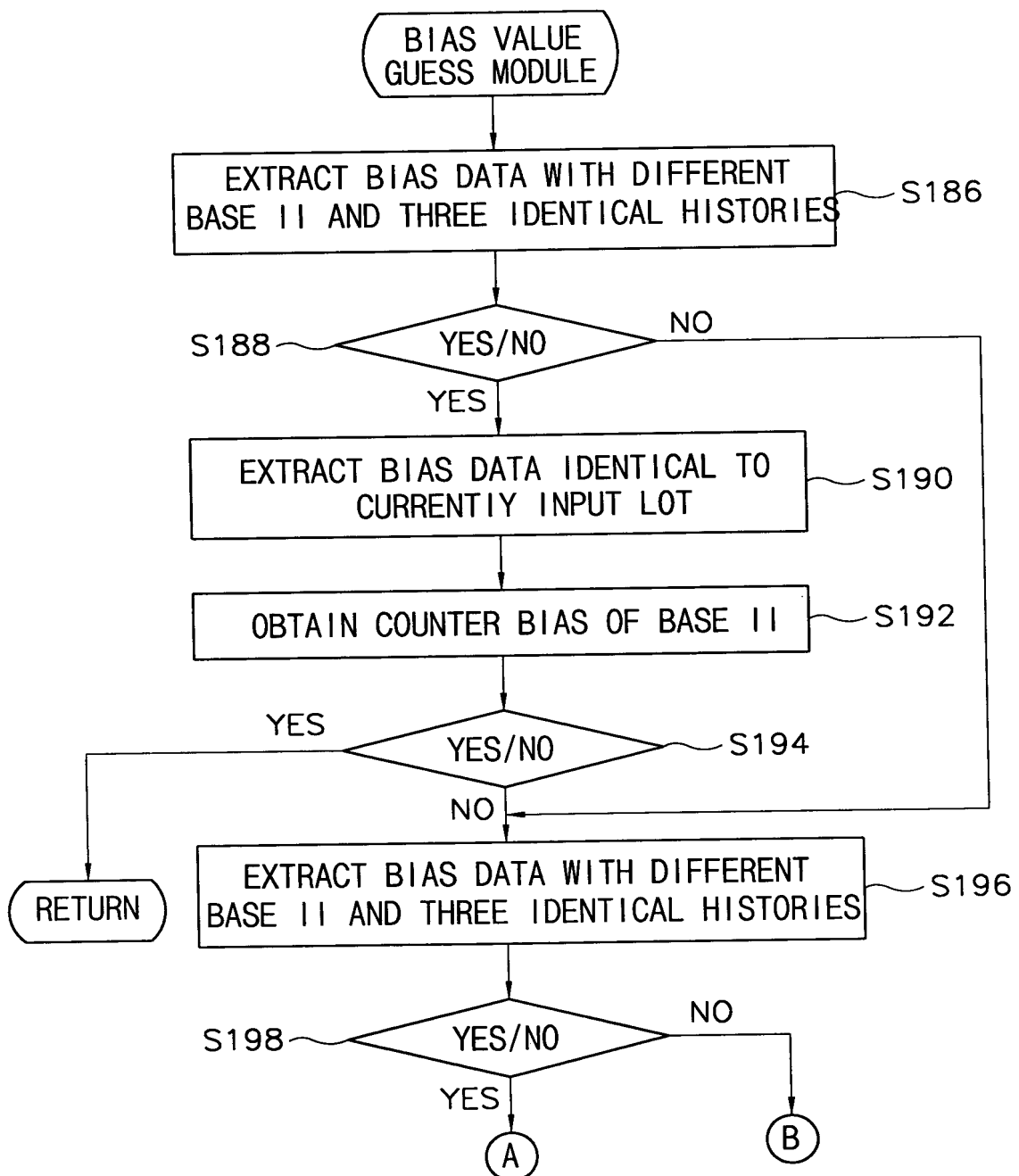


FIG. 18B

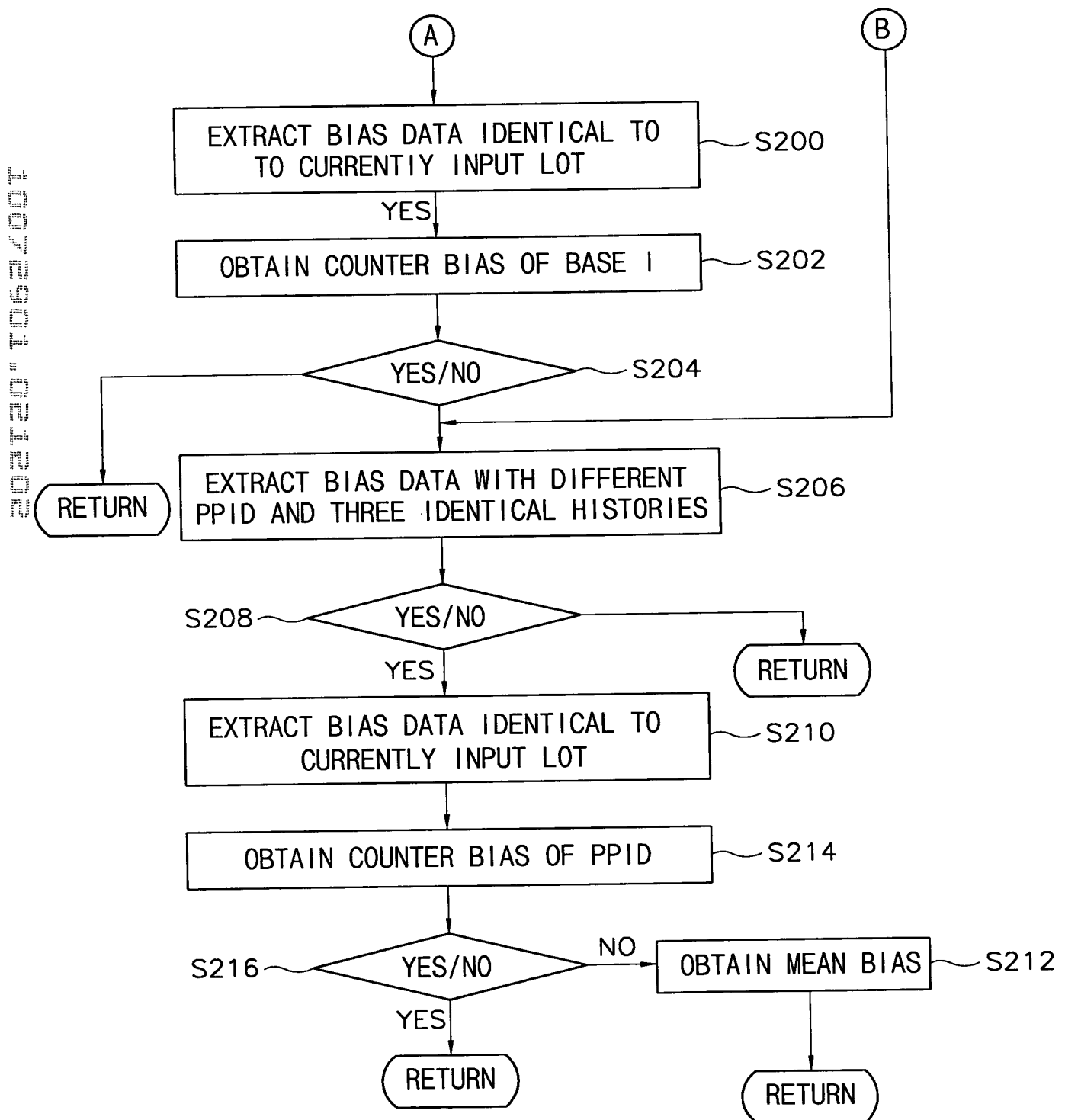


FIG. 19

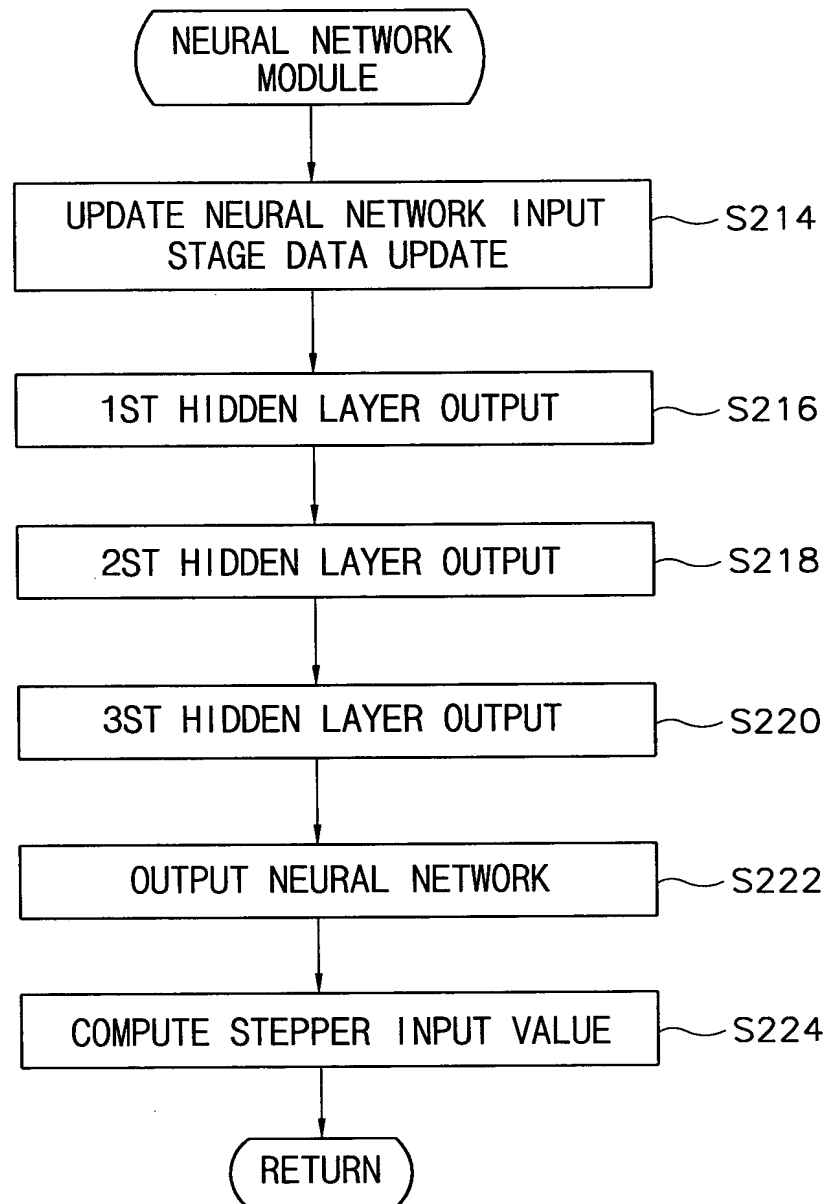


FIG. 20

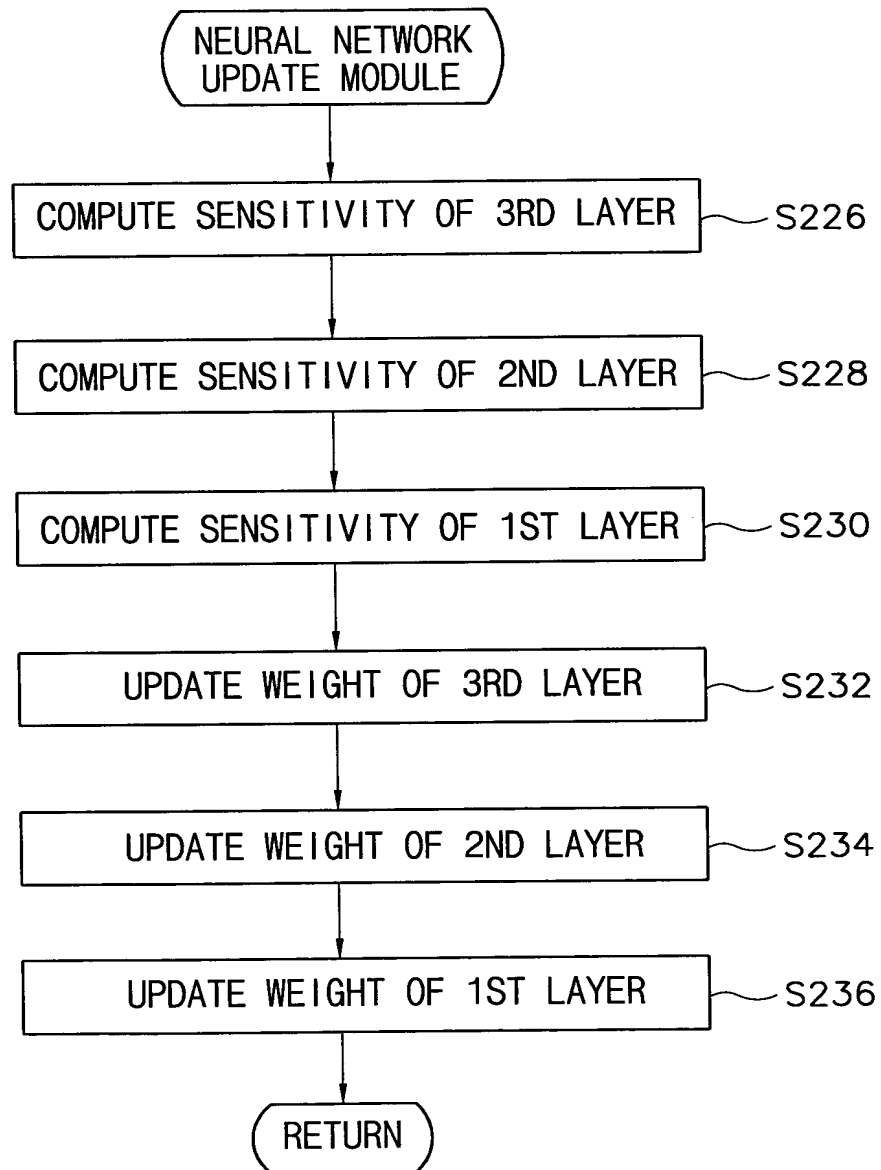
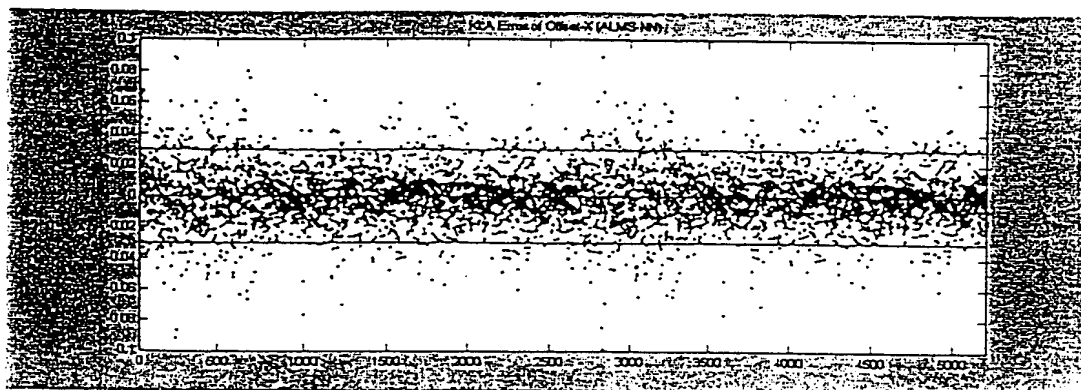
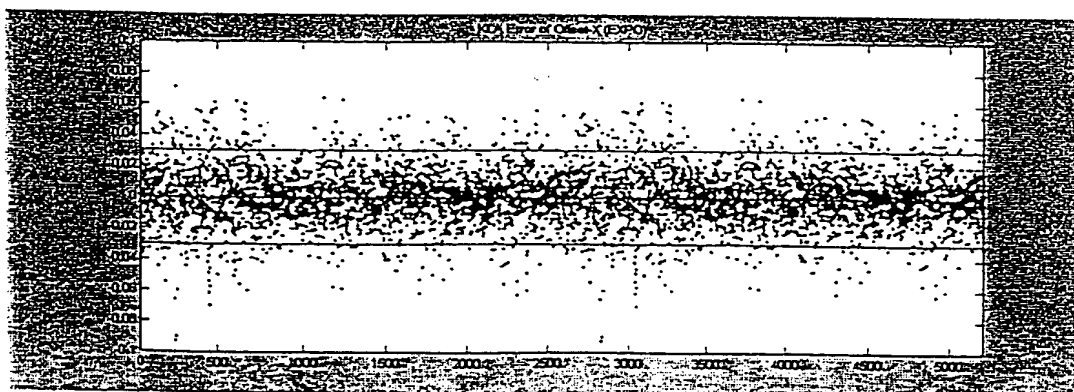


FIG. 21



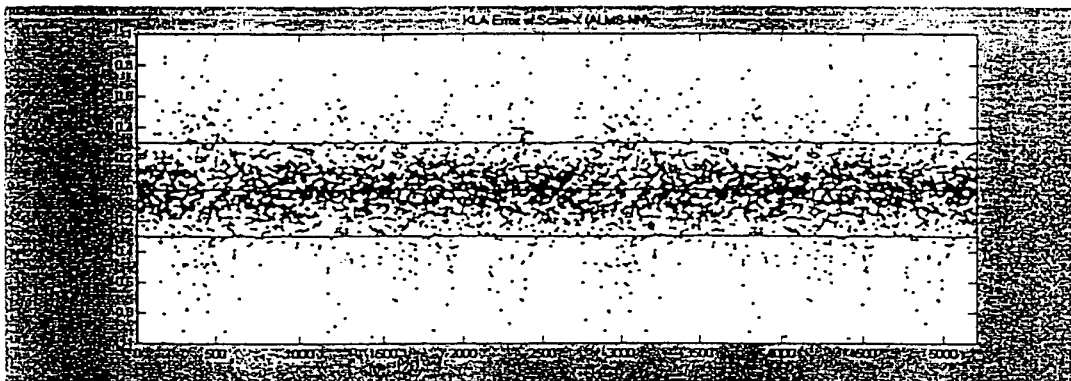
MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF OFFSET-X (ALMS-NN)



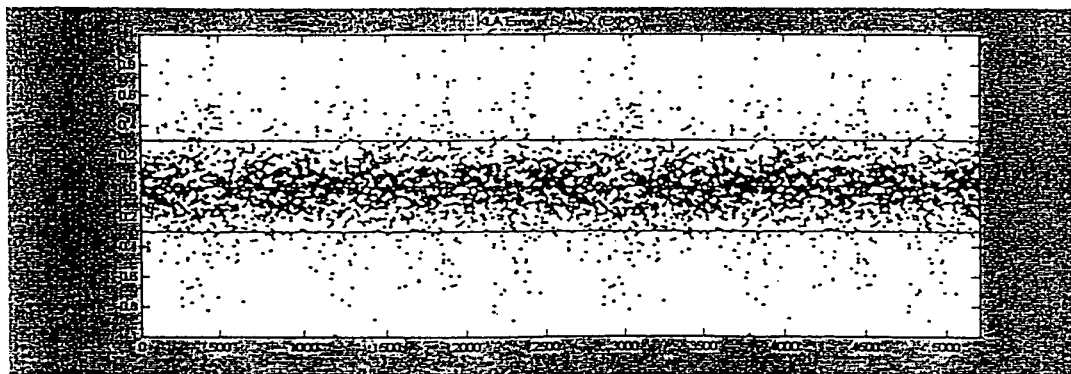
MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF OFFSET-X (TRADITIONAL SYSTEM)

10072301 04100  
2021 20 1052/00T

FIG. 22



MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF SCALE-X (ALMS-NN)

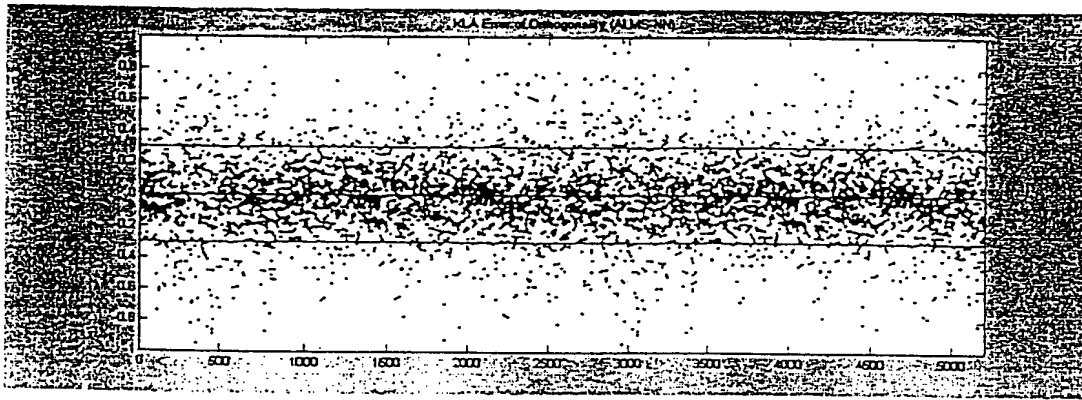


MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF SCALE-X (TRADITIONAL SYSTEM)

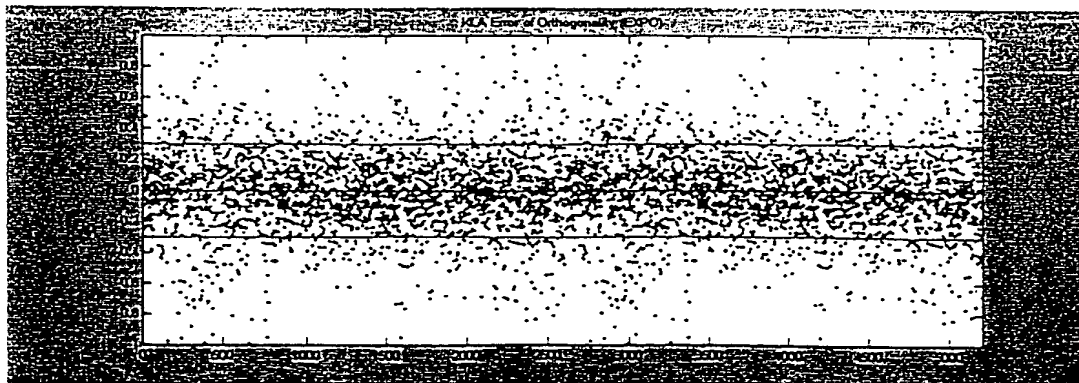
202120" T0527001



FIG. 23



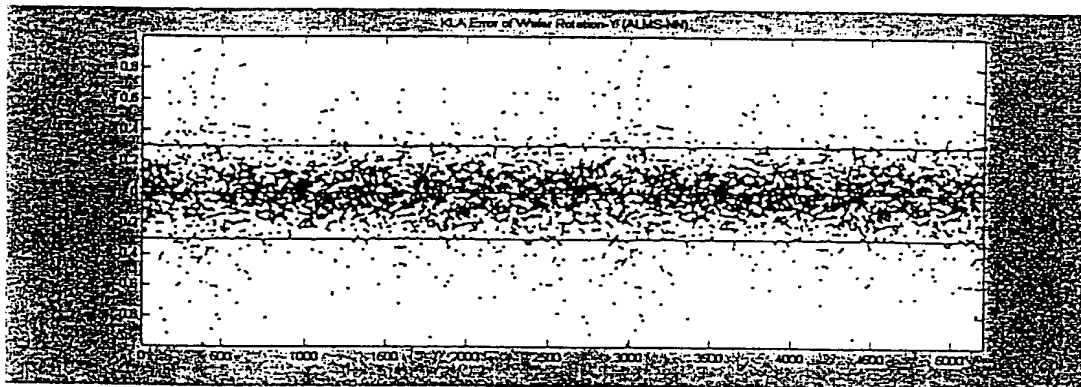
MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF ORTHOGONALITY (ALMS-NN)



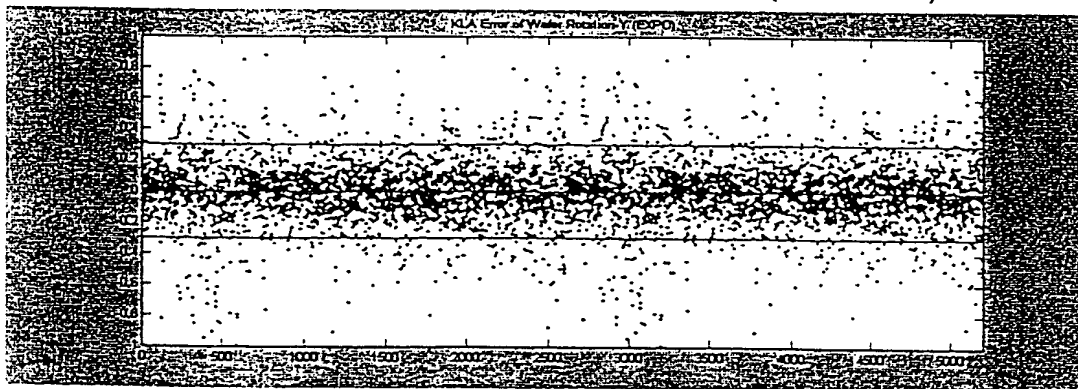
MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF ORTHOGONALITY (TRADITIONAL SYSTEM)

2007-10-22/001

FIG. 24

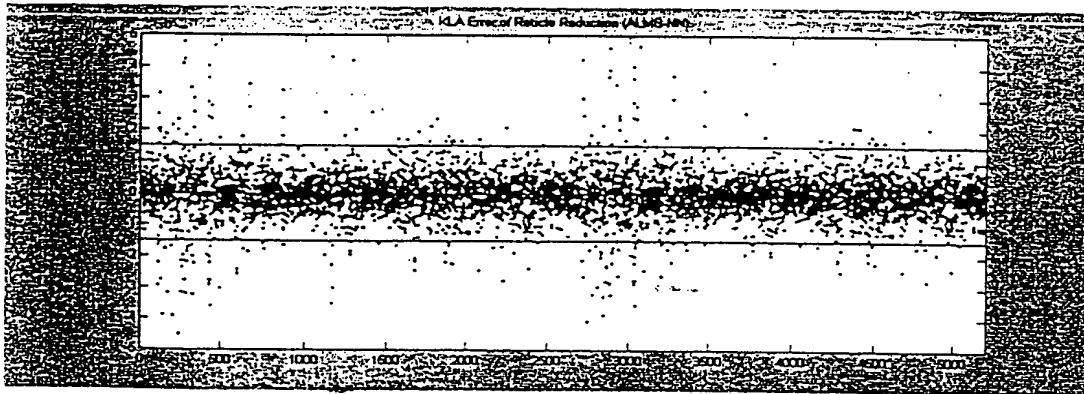


MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF WAFER ROTATION-Y (ALMS-NN)

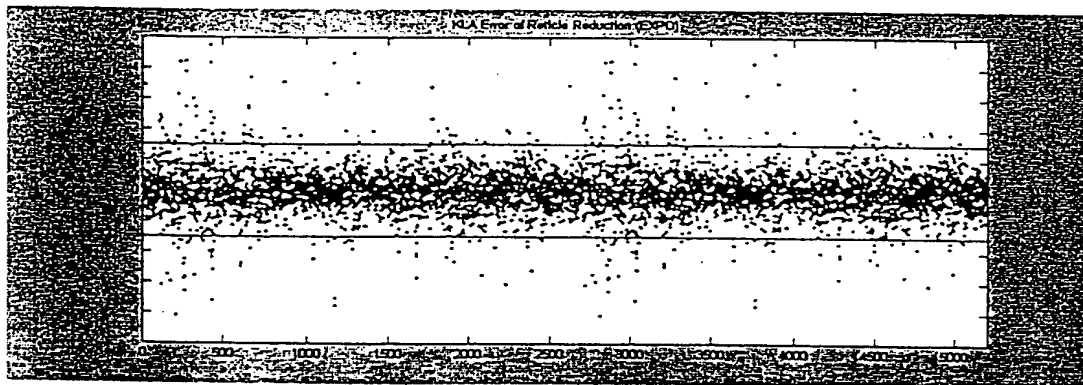


MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF WAFER ROTATION-Y (TRADITIONAL SYSTEM)

FIG. 25



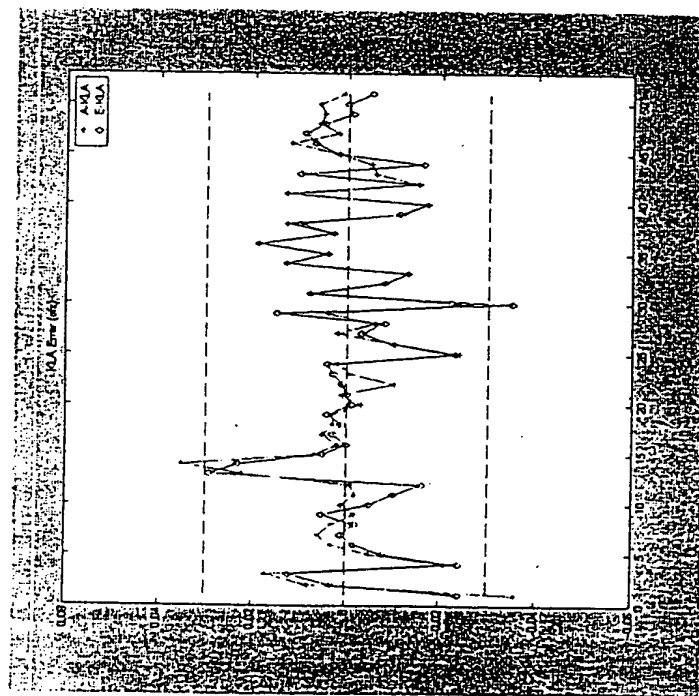
MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF RETICLE REDUCTION (ALMS-NN)



MEASUREMENT ERROR DISTRIBUTION OF MEASURER  
INSTRUMENT OF RETICLE REDUCTION (TRADITIONAL SYSTEM)

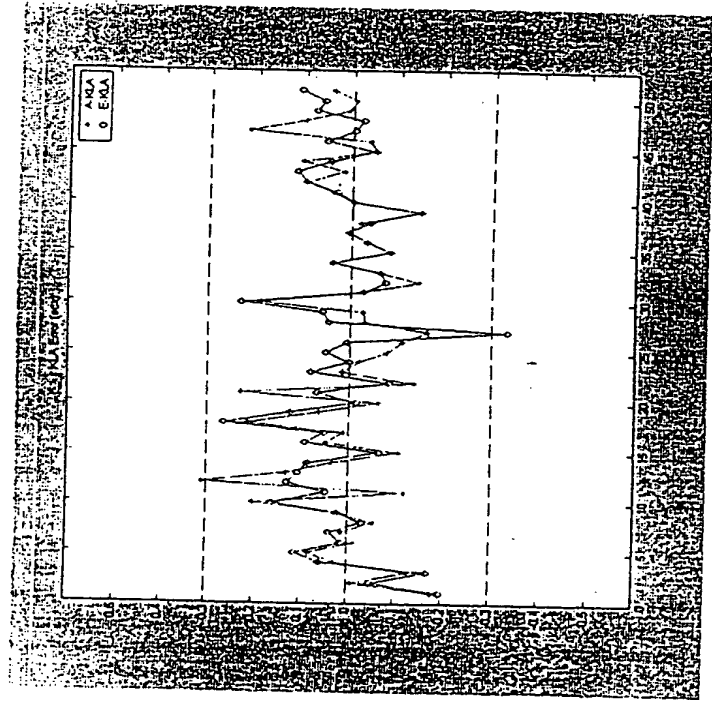
2023-10-23 10:00:00

FIG. 26



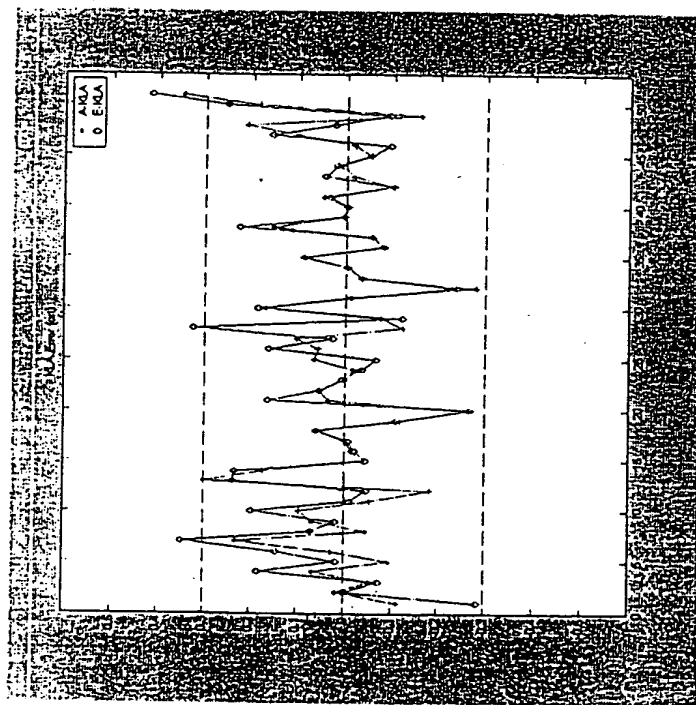
MEASUREMENT ERROR COMPARISON OF MEASURER  
INSTRUMENT OF OFFSET-X

FIG. 27



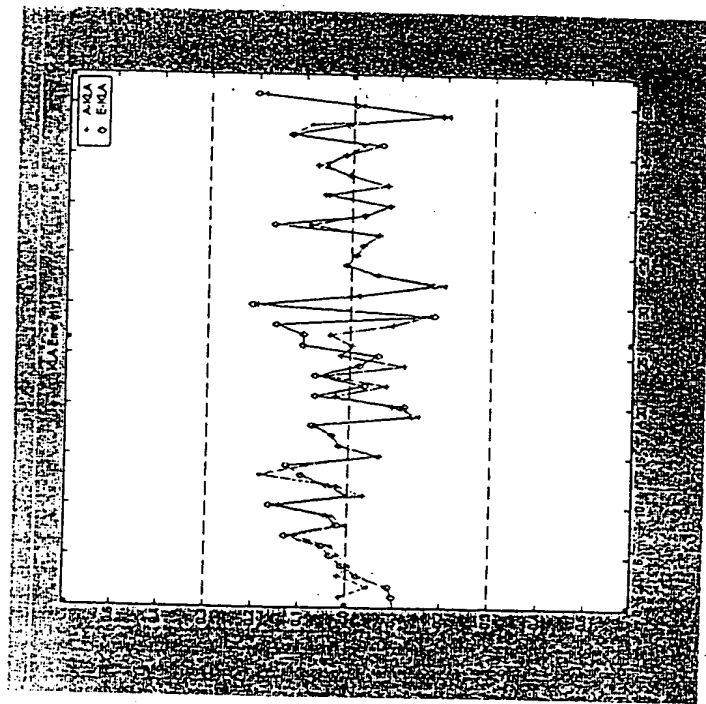
MEASUREMENT ERROR COMPARISON OF MEASURER  
INSTRUMENT OF SCALE--X

FIG. 28



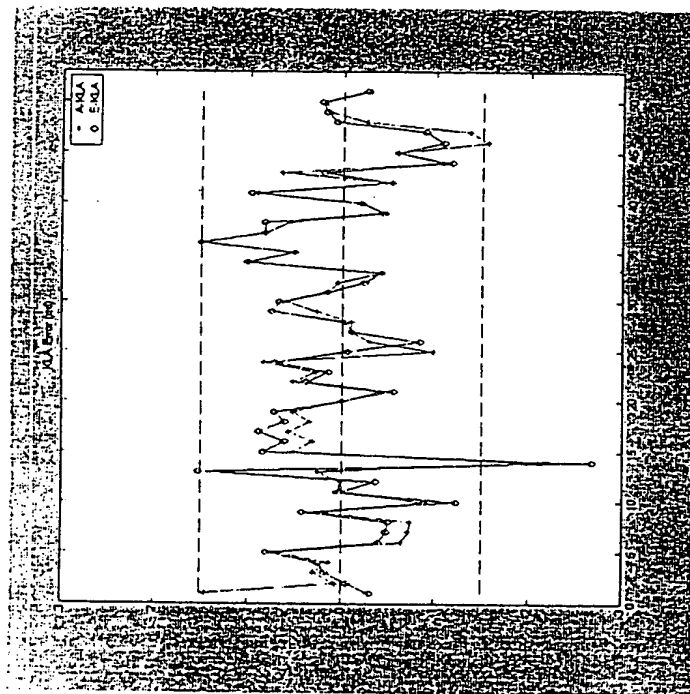
MEASUREMENT ERROR COMPARISON OF MEASURER  
INSTRUMENT OF ORTHOGONALITY

FIG. 29



MEASUREMENT ERROR COMPARISON OF MEASURER  
INSTRUMENT OF WAFER ROTATION-Y

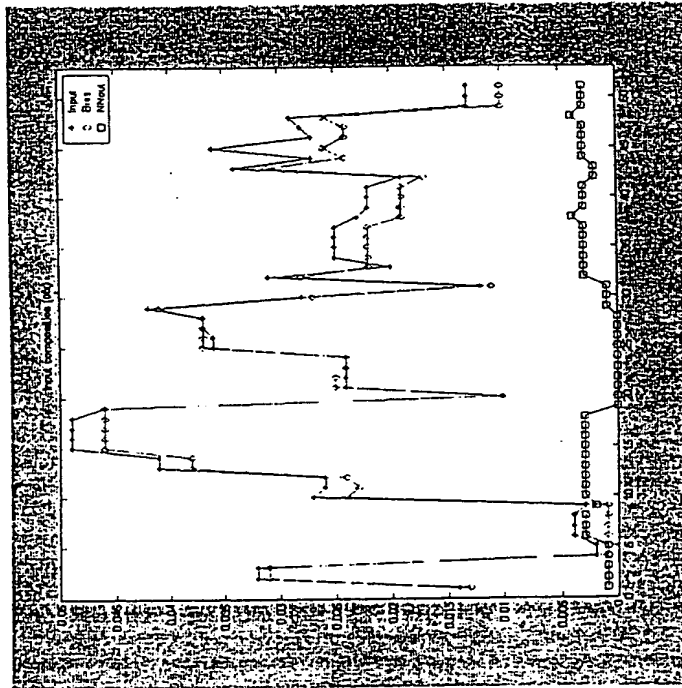
FIG. 30



MEASUREMENT ERROR COMPARISON OF MEASURER  
INSTRUMENT OF RETICLE REDUCTION

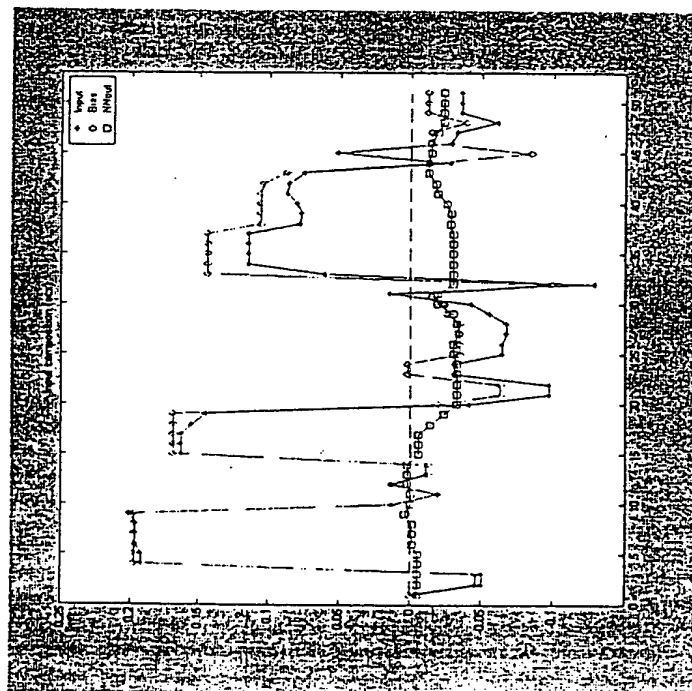


FIG. 31



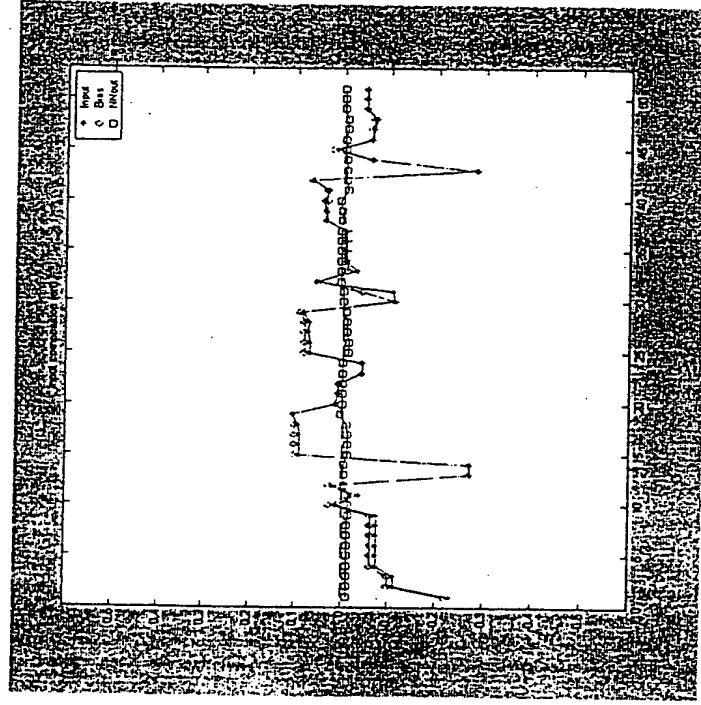
APPARATUS INPUT VALUE FORMAT OF OFFSET-X

FIG. 32



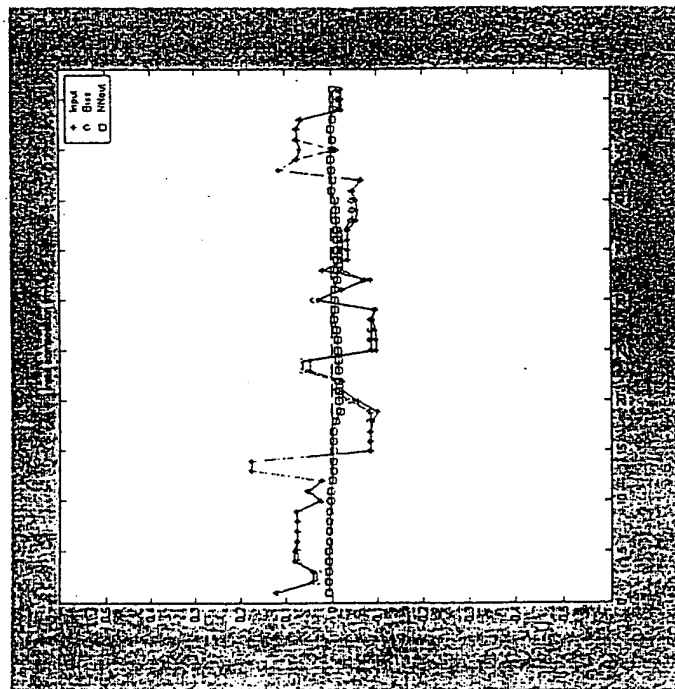
APPARATUS INPUT VALUE FORMAT OF SCALE-X

FIG. 33



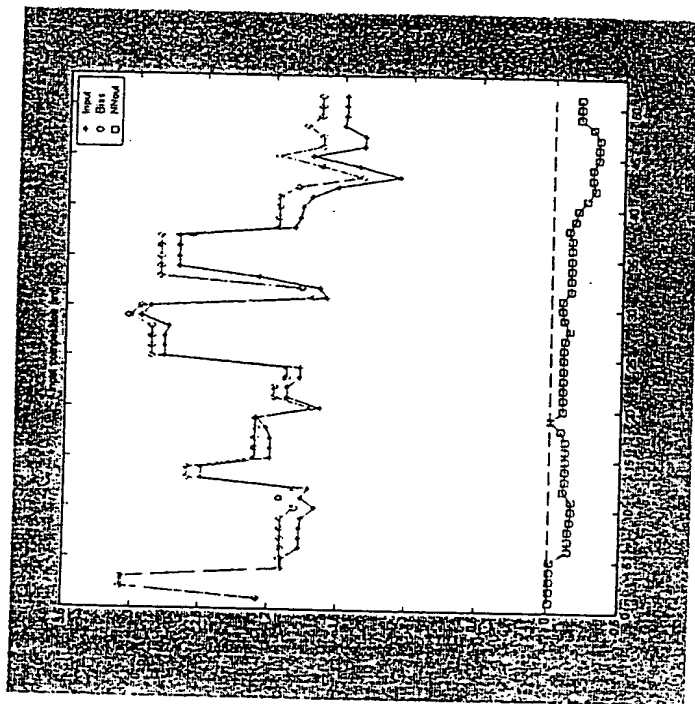
APPARATUS INPUT VALUE FORMAT OF ORTHOGONALITY

FIG. 34



APPARATUS INPUT VALUE FORMAT OF WAFER ROTATION-Y

FIG. 35



APPARATUS INPUT VALUE FORMAT OF RETICLE REDUCTION